

## ADSORPTION OF H<sub>2</sub>O ON CLEAN AND ON BORON-CONTAMINATED Rh SURFACES

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The adsorption and dissociation of H<sub>2</sub>O on Rh(111) and Rh foil surfaces have been studied in UHV using Auger electron, electron energy loss (in the electronic range) and thermal desorption spectroscopy. H<sub>2</sub>O adsorbs weakly on clean Rh samples at 110 K. The adsorption is accompanied by the appearance of a broad loss feature at 14–14.5 eV. At higher exposures new losses appeared at 8.6 and 10.5 eV. The desorption of H<sub>2</sub>O took place in two stages, with  $T_p = 183$  K ( $\beta$ , chemisorption) and 158 K ( $\alpha$ , multilayer formation). There was no indication of dissociation of H<sub>2</sub>O on a clean Rh(111) surface. Similar results were obtained for a clean Rh foil. However, when small amounts of boron segregated on the surface of Rh, they exerted a dramatic influence on the adsorptive properties of this surface and caused the dissociation of H<sub>2</sub>O. This was exhibited by the formation of H<sub>2</sub>, by the buildup of surface oxygen, by the appearance of an intense new loss at 9.4 eV, identified as B–O surface species, and by the development of “boron-oxide”-like Auger fine structure.

### 1. Introduction

We recently found that Rh supported on TiO<sub>2</sub> effectively catalyses the H<sub>2</sub>O + CO reaction to produce hydrocarbons and oxygenated compounds [1]. In addition, Rh/TiO<sub>2</sub> proved to be active in photocatalytic water splitting [2,3] and in the photocatalytic H<sub>2</sub>O + CO<sub>2</sub> reaction [4,5]. In order to understand the role of Rh in the activation of the water molecule, and to evaluate the effect of the TiO<sub>2</sub> support, it appeared inevitable to learn more about the interaction of H<sub>2</sub>O with Rh surfaces. Apart from a short conference abstract [6], no literature data are to be found on adsorption of H<sub>2</sub>O on Rh surfaces under UHV conditions.

The interaction of H<sub>2</sub>O with clean metal surfaces has been the subject of a number of detailed studies. Water vapour undergoes reversible molecular adsorption and desorption on Pt(111) and (100) [7–14], Pd(100) [15] and Ru(001) surfaces [16–19]. Dissociation occurs to a small extent (less than 6%) on Ir(110) [20]. A more significant dissociation, with the formation of hydro-

gen, has been observed on stepped Re and Re(0001) [21], Al(111) and (100) [22], Ti(001) and Fe(110) [24] surfaces. The dissociation of H<sub>2</sub>O exhibits a face specificity on Ni [25–28], Re [21] and Co [29] surfaces. On Ag(110) [30] and Cu(110) [31–33], H<sub>2</sub>O adsorption is molecular.

In the present study the adsorption of H<sub>2</sub>O is investigated on two Rh samples, Rh(111) and a polycrystalline Rh foil, by means of AES, EELS (in the electronic range) and TDS methods. Special emphasis is paid on the effects of boron impurity.

We recently observed that boron impurity segregating to a Rh surface can greatly alter its reactivity towards N-containing moieties such as N, CN and NCO [34–36]. A possible reason for this phenomenon is that boron forms a very strong bond with N, which can promote rupture of the C–N bond at high temperature and can prevent the associative desorption of N below 1100 K. We have also presented strong evidence that boron impurity on Rh surfaces (Rh(111) and Rh foil) can cause the dissociative adsorption of CO<sub>2</sub> at 300 K, which does not occur to a detectable extent on clean Rh surfaces [37, 38]. We expected a similar influence of boron in the case of H<sub>2</sub>O adsorption on Rh, too.

## 2. Experimental

The experiments were performed in a stainless steel UHV chamber equipped with several gas inlets, a single pass CMA (PHI) for AES, a 3-grid retarding field analyzer (VG) for LEED and a quadrupole mass analyzer (VG) to monitor the gas-phase composition. The vacuum system was evacuated with ion pumps and a titanium getter. The sample mounted on a manipulator can be cooled to 100–110 K and heated up to 1300 K.

For electron energy loss spectra the gun of CMA was used as a primary electron source with an energy of 70 eV and a beam current of 0.1–1.0  $\mu$ A. The backscattered electrons were analyzed with CMA. A modulation voltage of 0.1 eV was found to be the optimum for the used system. The velocity of taking a spectrum was varied between 0.4 and 4 eV/s. The exact positions of the peak maxima of energy losses were determined by a Keithley electrometer. Electron energy loss spectra were taken in  $dN(E)/dE$  form.

Two different Rh samples were used, a Rh(111) disk shape crystal (6  $\times$  1 mm, Material Research Co., 99.99% purity) and a polycrystalline Rh foil (10  $\times$  10 mm and 0.127 mm thick, Hicol Co., 99.9% purity). The initial cleaning procedure has been described previously [34–38]. It consisted of ion bombardment and annealing at 1270 K. As this Rh(111) sample has been used in a number of previous studies, its cleaning required no oxygen treatment. The major contaminants of Rh foil were B, P, S and C. The P, C and S were easily removed, but no complete elimination of boron was achieved even after

several cleaning cycles. The final thermal treatment in this case was performed at 700 K.

$H_2O$  was distilled three times before use; it was further purified by several cycles of freezing and pumping until the mass spectrometer displayed only water peaks. To avoid contamination from the walls of the UHV chamber,  $H_2O$  was introduced into the chamber through a stainless steel capillary with a diameter of 0.8 mm.

Segregation of boron was achieved by annealing the Rh foil at 750–1200 K. The level of surface boron is characterized by the relative intensity of the boron Auger signal,  $R_B = B_{178}/Rh_{302}$ . A crude calculation based on relative intensities of Auger signals (Handbook of Auger electron Spectroscopy) resulted in a value of  $3 \times 10^{14}$  borons/cm<sup>2</sup> at  $R_b \approx 0.09$ .

### 3. Results

#### 3.1. Rh(111) surface

##### 3.1.1. AES and TDS measurements

Fig. 1 illustrates the Auger electron spectrum of a cleaned Rh(111) surface. It exhibits only signals due to Rh. By careful examination of the energy region of boron at 170–180 K, we could detect only a break or a slight shoulder at 178 eV. This shoulder is practically always present on the AES of clean Rh samples. Exposure of this surface to 100 L  $H_2O$  at 300 K produced no change

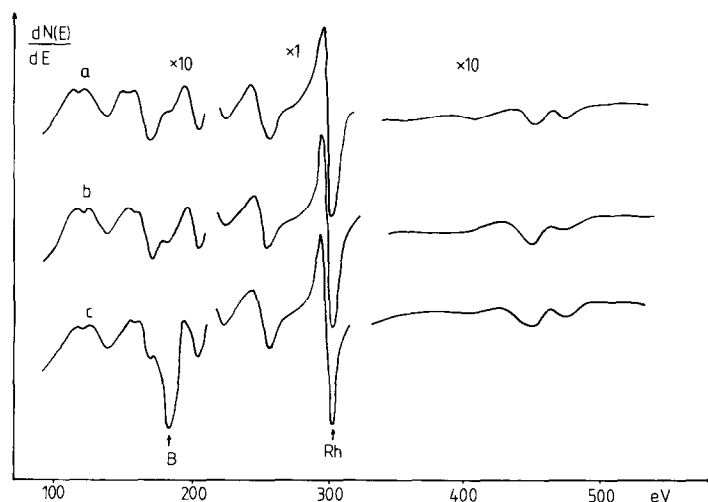


Fig. 1. Auger spectra of Rh samples: (a) clean Rh(111) ( $R_B < 0.003$ ); (b) clean Rh foil ( $R_B \sim 0.003$ ); (c) Rh foil contaminated with boron ( $R_B \sim 0.04$ ).

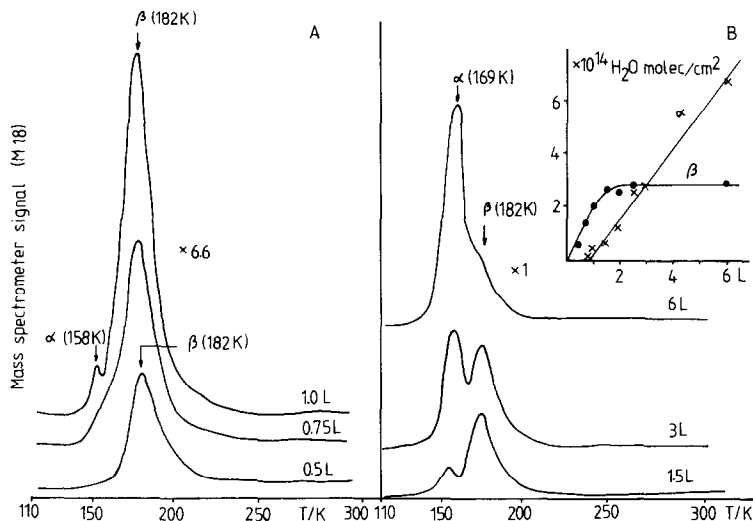


Fig. 2. (A) Thermal desorption spectra following  $\text{H}_2\text{O}$  adsorption on Rh(111) at 110 K. (B) Surface concentration of  $\text{H}_2\text{O}$  adsorbed in  $\alpha$  and  $\beta$  states as a function of  $\text{H}_2\text{O}$  exposure on a clean Rh(111) surface. Heating rate was  $10 \text{ K s}^{-1}$ .

in the Auger spectrum. In harmony with this, we could not detect any desorption products after exposure.

However, when  $\text{H}_2\text{O}$  was adsorbed at 110 K, two adsorption states of  $\text{H}_2\text{O}$  were detected. Fig. 2 shows a series of TD spectra in the low- and high-exposure regions. Lower exposures produced a single peak at 182–185 K, denoted by  $\beta$ . From 1 L, a new peak, denoted by  $\alpha$ , developed at 158 K.

The amount of  $\text{H}_2\text{O}$  desorbed in the  $\beta$  state increased linearly with the exposure up to 1.5 L, suggesting a mobile precursor model of adsorption (fig. 2). This state became saturated at about 2.5–3 L. Quantitative analysis of the peak areas, taking into account the pumping rate and the mass spectrometer and ion gauge sensitivity for  $\text{H}_2\text{O}$ , demonstrated that in this state the amount of adsorbed  $\text{H}_2\text{O}$  was approximately  $3 \times 10^{14}$   $\text{H}_2\text{O}$  molecules/ $\text{cm}^2$ , which corresponds to 0.19 ML surface concentration (1 ML = 1 monolayer =  $1.59 \times 10^{15}$  molecules/ $\text{cm}^2$  = the density of surface atoms on Rh(111)).

The lower-temperature  $\alpha$  peak at 158 K appeared at 65% saturation of the first layer (0.15 ML). The peak maximum shifts to higher temperature with increasing coverage. This indicates a zero-order process, which is in harmony with the sharp drop of the high-temperature edge of this peak (fig. 2). As saturation of this state is not attained, even at 10 L  $\text{H}_2\text{O}$  exposure, we identify this state with multilayer  $\text{H}_2\text{O}$ .

For a calculation of the activation energy for desorption in the  $\alpha$  state, the logarithm of the desorption rate at the leading edge was plotted against  $1/T$ : we obtained 43 kJ/mol.

The activation energy for desorption in the  $\beta$  stage was calculated by various methods. If it was estimated on the basis of simple first-order kinetics, assuming a pre-exponential factor of  $10^{13} \text{ s}^{-1}$ , we obtained a low value of 45 kJ/mol. Analysis of the data with the method of Chan et al. [39] or by the half order kinetics resulted in lower values.

It is important to point out that no H<sub>2</sub> desorption was observed from a clean Rh(111) surface after H<sub>2</sub>O adsorption.

### 3.1.2. EELS studies

The adsorption of H<sub>2</sub>O was also followed by EELS measurements. The EEL spectrum of a clean Rh(111) surface showed the same losses, at 2.6, 5.2–6.6, 17.8–18.6 and 24.5 eV (fig. 3a), as observed in our previous works [36,40,41]. On exposure of this surface to H<sub>2</sub>O at 110 K, a broad loss feature developed at 14–14.5 eV. No other loss was observed below 1.5 L H<sub>2</sub>O exposure. Above this value, i.e. when the multilayer developed, new losses appeared at 8.4 eV and at 10.5 eV. Their intensities increased with the rise of H<sub>2</sub>O exposure. At the same time, the intensity of the intrinsic loss of Rh at 5.2–6.6 eV clearly attenuated (fig. 3a).

In the subsequent measurements, a Rh(111) sample saturated with H<sub>2</sub>O at 110 K was heated to the designated temperature at a rate of 10 K/s, kept there for 1–2 s, and then allowed to recool to 110 K before its spectrum was recorded. Fig. 3b compares some spectra obtained in this way. The 8.4 and 10.5 eV losses started to attenuate at the beginning of heating, and disap-

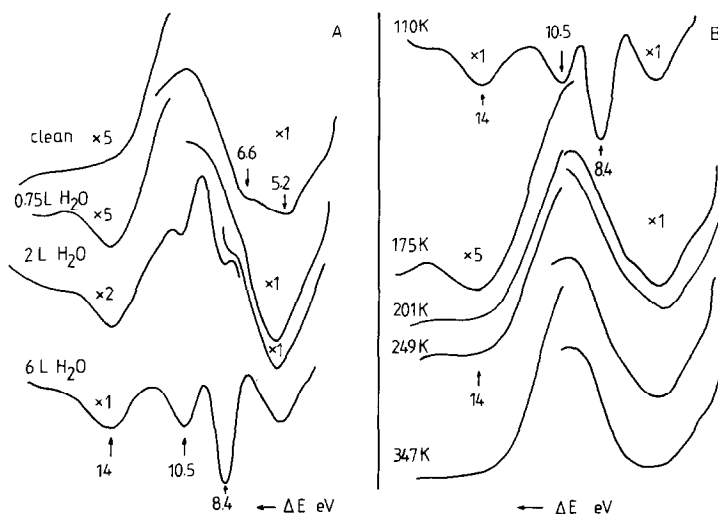


Fig. 3. EEL spectra of Rh(111) at different H<sub>2</sub>O exposures at 110 K (A) and after heating the sample exposed to 6 L H<sub>2</sub>O to different temperatures (B).  $E_p = 70 \text{ eV}$ ,  $I_b = 0.2\text{--}0.5 \text{ } \mu\text{A}$ .

peared at 175 K. The 14–14.5 eV loss was more stable; it was eliminated at about 200 K.

### 3.2. Rh foil containing boron impurity

#### 3.2.1. Adsorption at 100 K

The experiments were repeated with Rh foil. The purity of this sample is lower than that of Rh(111) and it required an extensive cleaning procedure to reduce the boron level to a minimal value. The lowest value we could attain for the Auger intensity ratio  $R_B = B_{178}/Rh_{302}$ , was  $\sim 0.003$  (fig. 1). The main characteristic features of the interaction of  $H_2O$  with this surface agreed quite well with those registered for a clean Rh(111) surface. The peak temperatures for the  $\alpha$  and  $\beta$  states remained practically unaltered on the boron-containing Rh surfaces, too. The amount of  $H_2O$  desorbed in the  $\beta$  state, however, decreased with the increase of  $R_B$  (fig. 4); for  $R_B = 0.08$  it was 1.5 times less than that from the clean Rh foil. A basically new feature was the formation of two high temperature states with  $T_p = 320$  and 370 K (fig. 4c). The amount of  $H_2O$  desorbed in these states was only a fraction of the  $\beta$  state (about 3%) and can be only detected by highly sensitive TDS measurements.

Another new feature was the evolution of  $H_2$  ( $T_p \sim 367$  K), which was never observed in the case of clean Rh(111) or Rh foil surfaces (fig. 5). The peak temperature of  $H_2$  desorption closely approached the highest values

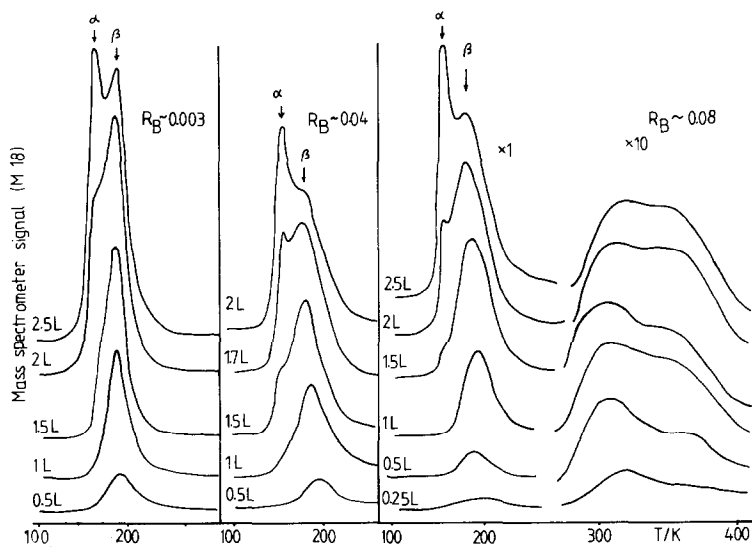


Fig. 4. Thermal desorption spectra following  $H_2O$  adsorption on the Rh foil of different boron impurity levels at 110 K.

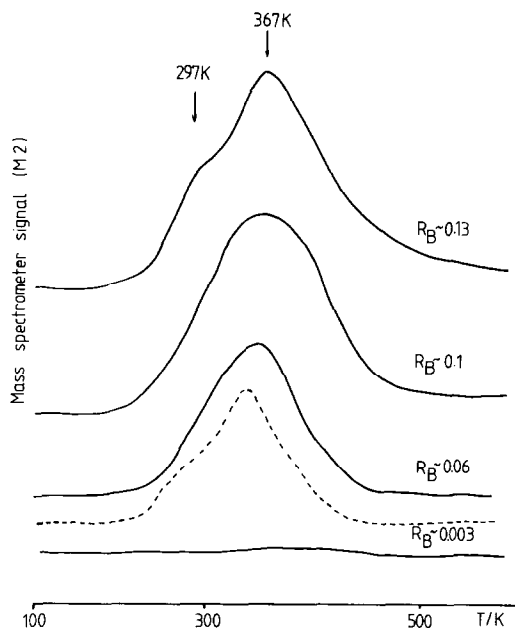


Fig. 5. Formation of  $H_2$  following 10 L of  $H_2O$  exposure at 110 K on Rh foil of different boron impurity levels. The dashed line represents the desorption of  $H_2$  following  $H_2$  adsorption on a clean Rh foil ( $R_B \sim 0.003$ ).

obtained after  $H_2$  adsorption on Rh(111) and Rh foil surfaces at low coverages ( $T_p \sim 360$ – $400$  K) [42–45]. This result suggests that a portion of the adsorbed  $H_2O$  dissociates during the adsorption or in the course of the heating of the adsorbed layer, very probably due to the effect of boron impurity on the surface. As the data in fig. 5 show, an increase in the  $R_B$  values, through annealing of the Rh foil at 850–1200 K, enhanced the amount of  $H_2$  evolved. At the highest boron impurity level, a second  $H_2$  desorption peak developed at 295 K. The amount of  $H_2$  evolved was calculated to be  $\sim 1 \times 10^{14}$  molecules/cm<sup>2</sup>, which means that at most  $\sim 25\%$  of chemisorbed  $H_2O$  decomposed on the surface.

The EEL spectra of a clean, and of a boron-contaminated Rh foil showed the same losses as were observed for clean Rh(111). There was no additional losses due to the presence of boron on the surface. Exposure of these surfaces to  $H_2O$  at 110 K produced losses similar to those in the case of Rh(111) (fig. 6). The intensity of the 14 eV loss was somewhat higher at saturation of the  $\beta$  state (2.5–3 L) in the presence of boron impurity ( $R_B \sim 0.08$ ) than for the clean Rh foil.

However, a significant difference was found when the EEL spectra were

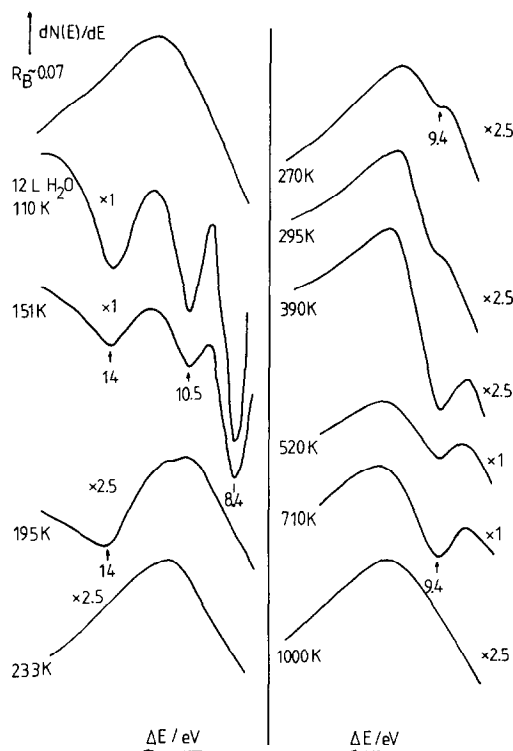


Fig. 6. EEL spectra of Rh foil ( $R_B \sim 0.08$ ) taken after heating the sample exposed to 12 L  $\text{H}_2\text{O}$  at 110 K to different temperatures.

registered after stepwise heating (at 10 K/s) of the adsorbed layer to higher temperatures (fig. 6). The development of a new loss at 9.4 eV in the EEL spectrum of boron-contaminated Rh surfaces can be clearly established at 270 K. The intensity of this loss attained a maximum at 640–700 K and decreased to an undetectable level above 950 K. In this case, the sample was kept at the designated temperature for 1–2 s. However, a significant increase in the intensity of the 9.4 eV loss can be obtained at lower temperature if the sample is kept there for sufficient time (see next section). Similarly to the clean surface the 10.5 and 8.4 eV losses were detectable up to 175 K. The loss at 14.0–14.5 eV was present up to 210 K.

### 3.2.2. Adsorption at 300–420 K

In this case we examined the interaction of  $\text{H}_2\text{O}$  with a boron-containing Rh surface by high-resolution Auger spectroscopy in the boron signal range 140–200 eV. The elemental boron KLL spectrum (fig. 7) shows an asymmetric feature in the  $dN(E)/dE$  mode; the positive and negative wings have very



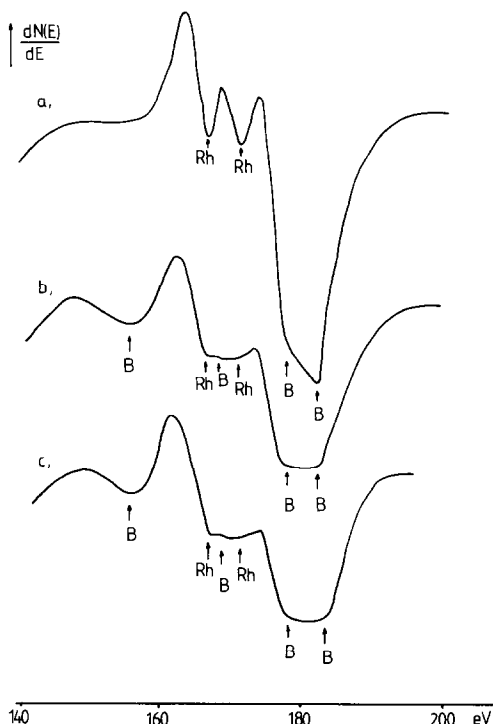


Fig. 7. High-resolution Auger spectra of boron-contaminated Rh foil ( $R_B \sim 0.07$ ) in the boron Auger signal range: (a) before  $H_2O$  adsorption, (b) after 50 L of  $H_2O$  exposure at 300 K, (c) sample (b) heated to 660 K ( $E_p = 2.5$  keV,  $I_b = 0.5$   $\mu$ A,  $V_{mod} = 1$  V).

different intensities. The peak displays two minima, at 179 and 182 eV. After the adsorption of 50 L of  $H_2O$  at 300 K, the intensities of the boron signals at 179 and 182 eV markedly decreased and two additional peaks developed, at 157 and 168–172 eV. The latter peak was superimposed on the Rh Auger structure present at 166 and 171 eV. When the  $H_2O$ -exposed sample was heated, no changes occurred in the structure or in the intensities of the Auger signals up to 660 K. The original shape of the elemental boron feature was regained after heating to about 1000 K.

Following the adsorption of  $H_2O$  on boron-containing Rh at 300 K, we also observed the high-temperature adsorption states of  $H_2O$  at 360 and 460 K. It can be seen from fig. 8a that the development of these states is strongly dependent on the surface concentration of boron. The amount of  $H_2O$  desorbed from a saturated layer at  $R_B = 0.07$  corresponds to about  $1.0 \times 10^{13}$  molecules/cm<sup>2</sup>. The formation of  $H_2$  also occurred in this case with  $T_p = 392$  K (fig. 8c). On interruption of the heating after desorption of  $H_2$  at 640 K, the

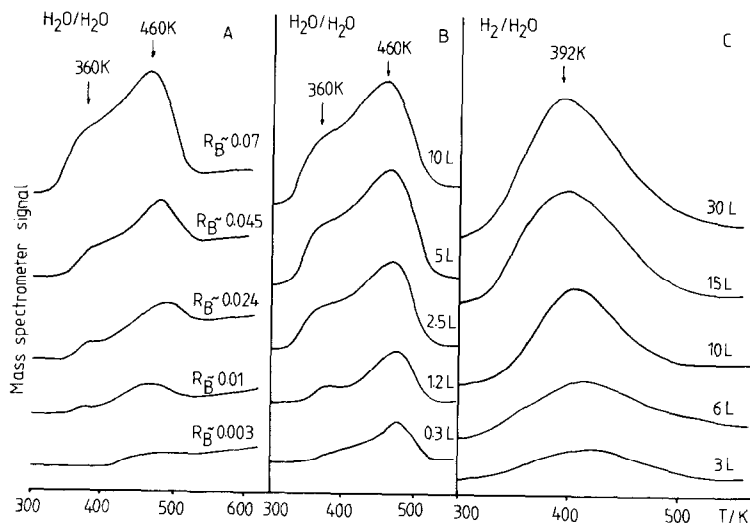


Fig. 8. (A) Thermal desorption spectra following 10 L  $\text{H}_2\text{O}$  adsorption on Rh foil of different boron impurity levels at 300 K. (B) Effect of  $\text{H}_2\text{O}$  exposures at 300 K on the desorption of  $\text{H}_2\text{O}$  from Rh foil ( $R_B \sim 0.07$ ). (C) Formation of  $\text{H}_2$  following 10 L of  $\text{H}_2\text{O}$  exposure at 300 K ( $R_B \sim 0.07$ ).

oxygen Auger signal was detected at 513.7 eV. On exposure of this surface to  $\text{H}_2\text{O}$ , less  $\text{H}_2$  was formed during the thermal desorption. After the third  $\text{H}_2\text{O}$  exposure, the  $\text{H}_2$  produced was only just detectable.

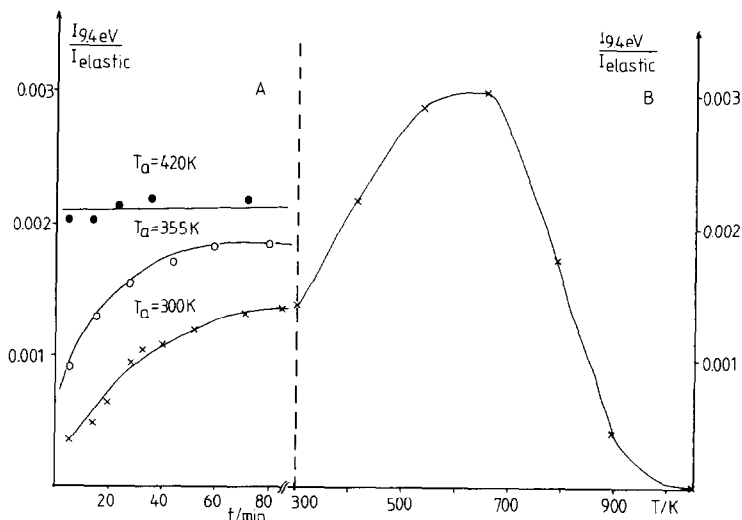


Fig. 9. Changes in the intensity of the 9.4 eV loss at different temperatures (A) and after heating the sample exposed to  $\text{H}_2\text{O}$  at 300 K to higher temperatures (B). Heating rate was  $\sim 10$  K/s and the sample was kept at the designated temperature for  $\sim 2$  s.

H<sub>2</sub>O adsorption at 300 K produced a perceptible loss feature at 9.4 eV in the EEL spectrum only at higher H<sub>2</sub>O exposure (< 10 L). Intensification of this loss was achieved when the sample was kept at 300 K for a longer period, or was heated to higher temperature, or a higher adsorption temperature was applied (fig. 9).

## 4. Discussion

### 4.1. H<sub>2</sub>O adsorption and desorption on a clean Rh(111) surface

H<sub>2</sub>O adsorbs readily on the Rh(111) surface at 110 K. By means of thermal desorption measurements we distinguished two adsorption states. The more strongly bonded one ( $T_p = 182\text{--}185$  K) can be attributed to the weakly chemisorbed first monolayer ( $\beta$  state). From the relationship between surface coverage ( $\beta$ ) and exposure, it appears that the sticking coefficient is constant for submonolayer coverages (fig. 2). From this correlation the sticking probability is estimated to be near unity (0.78). Similar values were obtained in the case of Pt(100) [11], Ir(110) [20] and Cu(110) surfaces [33]. The amount of H<sub>2</sub>O desorbed in this state increased linearly with exposure up to 1.5 L, suggesting a mobile precursor model of adsorption. From the shape of the desorption peak ( $\beta$ ), we may assume an attractive interaction between adsorbed molecules: the full width of the desorption peak at half maximum is only 15–22 K (fig. 2). Calculation of the activation energy for desorption of the  $\beta$  state on the basis of first-order kinetics gives a low value, 45 kJ/mol. Similar values (42–51 kJ/mol) were obtained in other cases [8,15,19,25] when a first-order desorption process was assumed. We note that in the majority of cases, the peak relating to desorption of the first layer is shifted to higher temperatures as the coverage increases. The fact that no shift was observed for the  $\beta$  state in the present case may be due to the relatively low coverage (saturation of this state is attained already at 0.2 ML), which prevented the recording of a sufficient number of desorption curves. The same situation existed for the Pd(100)–H<sub>2</sub>O [15] system, where saturation of the first layer occurred at 0.25 ML. Similar behaviour was exhibited by Re(0001) [21], on which no shift of the  $\beta$  state was observed within the experimental accuracy. Reconstruction of the adsorbed layer, changes at the adsorption sites, or the beginning of dissociation of water during the desorption were proposed as possible reasons. In the present case, the latter possibility can be excluded with certainty.

With increase of the coverage, a second peak developed at 158–169 K; this corresponds to the formation of a multilayer of H<sub>2</sub>O. The zero-order desorption energy of this peak ( $\alpha$ ), 43 kJ/mol, is in good agreement with the value obtained for the desorption of multilayer H<sub>2</sub>O from other metals, e.g. on Pt(111) [8], Ni(111) [25], Pd(100) [15], Cu(110) [33], Ru(001) [19] and Ir(110)

[20] surfaces. This agreement suggests that the desorption energy is independent of the metal and is related to the sublimation energy of ice,  $\sim 50$  kJ/mol.

We can assume that, similarly to the other metals, H<sub>2</sub>O is bound to the Rh(111) via one of the lone pair orbitals and the second lone pair orbital is used for hydrogen bonding to adjacent H<sub>2</sub>O [11,12,17,19,21,27]. The formation of the multilayer may occur on top of this primary layer. The surface concentration for the first layer ( $\beta$  state) at saturation is (within an accuracy of  $\pm 50\%$ )  $\sim 3 \times 10^{14}$  H<sub>2</sub>O molecules/cm<sup>2</sup>, which corresponds to a surface coverage of  $\theta = 0.19$  relative to the number of surface metal atoms, i.e.  $1.59 \times 10^{15}$  atoms/cm<sup>2</sup>. This value is almost the same as that for Pd(100) [15], but considerably less than those for Pt(111) [8], Ru(001) [19] and Re surfaces [21].

The adsorption of H<sub>2</sub>O on a Rh(111) surface at 110 K produced new losses at 8.4, 10.5 and 14–14.5 eV in the electronic range in the EEL spectrum. At low exposures, where mainly the chemisorbed phase is present, only one peak developed at 14–14.5 eV. The peaks at 8.4 and 10.5 eV appeared when the multilayer phase was formed at higher exposures.

When Rh(111) exposed to H<sub>2</sub>O at 110 K was heated, the 8.4 and 10.5 eV losses were eliminated by 175 K, while the 14 eV loss vanished at around 201 K. These values are in accord with the thermal desorption data for the multilayer and the chemisorbed state (fig. 2), supporting our view that the 14 eV loss is caused by chemisorbed H<sub>2</sub>O, while the three-peak structure, at 8.4, 10.5 and 14 eV, is due to formation of the multilayer. It is important to mention that no other losses developed in the EELS of Rh(111), even on high H<sub>2</sub>O exposure ( $\sim 100$  L) and/or at the higher temperature of 300 K.

To establish the origin of the above losses, it is helpful to consider that the highest occupied orbitals in the free H<sub>2</sub>O molecule are at 17.17 eV (1B<sub>2</sub>), 13.15 eV (3A<sub>1</sub>) and 11.68 eV (1B<sub>1</sub>) below the vacuum level [46]. These orbitals are measured in UPS for the adsorbed H<sub>2</sub>O molecule on clean metals at 6.5–7.4, 9.0–9.5 and 12.2–13.7 eV referenced to the Fermi level [13,26,33]. The fact that we found three losses for adsorbed H<sub>2</sub>O in the EEL spectrum of Rh fits in well with this picture. Accordingly, we tentatively assign the 8.4, 10.5 and 14 eV losses to the intramolecular electronic excitation from 1B<sub>1</sub>, 3A<sub>1</sub> and 1B<sub>2</sub>, respectively, to the unoccupied 4A<sub>1</sub> orbital of H<sub>2</sub>O, which is situated near above the Fermi level. The appearance of the loss at  $\sim 14$  eV (1B<sub>2</sub>  $\rightarrow$  4A<sub>1</sub>) in the chemisorbed state also indicates that the H<sub>2</sub>O is adsorbed as a molecule, as the 1B<sub>2</sub> provides the bond between the hydrogen and oxygen holding the molecule together [13].

#### 4.2. H<sub>2</sub>O adsorption and desorption from clean and from boron-contaminated Rh foil

The main characteristics of H<sub>2</sub>O adsorption and desorption for a clean

polycrystalline Rh foil, as established by TDS and EELS measurements, agreed quite well with those for clean Rh(111). However, when boron was allowed to segregate onto the surface, significant differences were observed. Although the amount of H<sub>2</sub>O adsorbed in the  $\beta$  state increased only slightly with increase of the boron impurity level, as indicated by the higher intensity of the 14 eV loss, less H<sub>2</sub>O desorbed in the  $\beta$  state. The peak temperature,  $T_p = 185$  K, however, remained unaltered. Completely new features were the formation of adsorption states with  $T_p = 320$  K and 370 K, and the formation of H<sub>2</sub> with  $T_p = 367$  K. The latter indicated that adsorbed H<sub>2</sub>O underwent dissociation on the boron-containing Rh surface. The amount of H<sub>2</sub> increased with the relative intensity of the boron Auger signal, but a linear correlation was not found. At a high boron concentration,  $R_B = 0.08$ , almost  $\sim 25\%$  of chemisorbed H<sub>2</sub>O dissociated on the surface.

The drastic effect of boron impurity on the behaviour of H<sub>2</sub>O on Rh exhibited in the EEL spectra. Although the same losses appeared in the EEL spectra of clean and boron-contaminated Rh foil following H<sub>2</sub>O adsorption to 110 K, and they exhibited the same thermal behaviour as that observed for the Rh(111) surface, a new loss developed at 9.4 eV at about 270 K. This showed maximum intensity at 650 K and disappeared only above 950 K.

In order to assign this loss to a particular surface species, the interaction of O<sub>2</sub> was also investigated by EEL spectroscopy [47]. On clean Rh surfaces the adsorption of O<sub>2</sub> apparently intensified only the intrinsic loss of Rh at 5–6 eV, and produced no other detectable losses, even at higher exposure at 100 or 300 K. In the presence of boron impurity, however, an intense new loss appeared at 9.4 eV. This was detected first at 200 K; it exhibited an identical temperature-dependence to that of the 9.4 eV loss produced by H<sub>2</sub>O adsorption on the same surface.

The 9.4 eV loss also appeared when the boron-contaminated Rh surface was exposed to CO<sub>2</sub> at or above 300 K [37,38]. When all these observations are taken into account, it seems plausible that the 9.4 eV loss is due to the formation of some kind of boron-oxide surface species.

The conclusion is supported by the EELS study of the interaction of polycrystalline boron with oxygen [48]. The most intense loss was found at 8.6 eV. Its intensity markedly increased with the oxygen exposure. We note here that boron was found to be resistant to oxidation by traditional UHV exposure techniques. Therefore O<sub>2</sub> was introduced into the system through the ionizer of a sputter ion gun [48]. The comparison of the two systems illustrates the higher reactivity of boron in the surface layer of Rh and/or the importance of the Rh matrix in the surface reaction.

The formation of the B–O species is also supported by high-resolution Auger spectroscopic measurements. After the adsorption of H<sub>2</sub>O at above 270 K, two new Auger transitions appeared at 157 and 168–172 eV. At the same time, the intensities of the elemental boron Auger signals at 179 and 182 eV

decreased. These features are very similar to those observed following the oxidation of polycrystalline boron [48] and can be attributed to the formation of B<sub>2</sub>O<sub>3</sub> [49,50]. A somewhat similar change in the structure of the boron Auger signals was registered on the adsorption of O<sub>2</sub> on boron-contaminated Rh surface [47,51]. In the case of H<sub>2</sub>O adsorption, the intensities of the “oxide-like” Auger transitions relative to the elemental boron feature were less than after O<sub>2</sub> adsorption at saturation. This indicates that only part of the boron is involved in the dissociation of H<sub>2</sub>O.

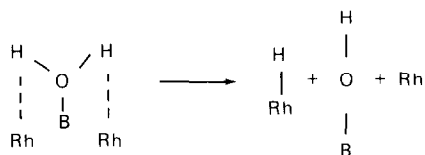
The formation of a compound, boron oxide, is revealed by the position of the oxygen Auger signal. In the case of a clean Rh surface, the oxygen Auger feature appears at 520 eV; on the boron-contaminated Rh, however, the adsorption of H<sub>2</sub>O and O<sub>2</sub> produces an Auger feature at 513.7 eV.

These results indicate that H<sub>2</sub>O dissociates on boron-contaminated Rh surfaces, producing adsorbed H and boron-oxide species. The driving force of this surface reaction is the high stability of the B–O bond; the dissociation energy of this bond is 787 kJ/mol [52].

As regards the dissociation of chemisorbed H<sub>2</sub>O, we propose the following reaction sequences. It is reasonable to assume that the boron interacting with adsorbed H<sub>2</sub>O via a lone pair electron of the oxygen atom of the H<sub>2</sub>O molecule:



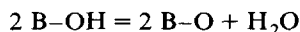
exerts a stabilizing effect on it. This feature is apparently exhibited in the thermal desorption of H<sub>2</sub>O; new adsorption states are formed with  $T_p = 320$  and 370 K. The amount of H<sub>2</sub>O desorbed in these states is very small,  $\sim 1 \times 10^{13}$  H<sub>2</sub>O molecules/cm<sup>2</sup>; which is probably due to the fact that the H<sub>2</sub>O molecule is bound so strongly to the boron that, instead of desorbing, it mainly dissociates. However, the existence of stabilized H<sub>2</sub>O was not seen in the EEL spectra as the characteristic low for chemisorbed H<sub>2</sub>O ( $\sim 14$  eV) was detected only up to 210 K. This could be due to the low concentration of species (A) on the surface. An alternative explanation is that decomposition of this surface complex occurred around 200 K:



producing B–OH and Rh–H species.

As the 9.4 eV loss attributed to the B–O species was first detected at 270 K,

we may conclude that the dissociation of chemisorbed H<sub>2</sub>O, or the disproportionation of B–OH species,



starts at around this temperature, and occurs at maximum rate above 300 K. We mention here that in the case of the Al–H<sub>2</sub>O system the onset of this transformation of hydroxide to oxide was observed at 240 K [53]. The recombination reaction



can also occur, but this process does not lead to the formation of B–O species.

As the peak temperature for H<sub>2</sub> desorption from a boron-contaminated surface agreed quite well with that determined on clean Rh surfaces [42–45], we can conclude that hydrogen is bonded to the Rh, and its formation is a desorption rate limited process.

As concerns the significant changes occurring in the intensity of the 9.4 eV loss above 450–500 K (when all the desorption processes have been completed), these have probably no connection with the surface reactions of adsorbed H<sub>2</sub>O, as the same features were experienced following O<sub>2</sub> adsorption on a boron-containing Rh surface [47]. It is very likely that this behaviour is due to the transformation or polymerization of B–O into another boron-oxide species. We will deal with this process in detail elsewhere [47].

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